

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 9516

Norio KIMURA et al. : Attorney Docket No. 2003-0865

Serial No. 10/601,789 : Group Art Unit 3723

Filed June 24, 2003 : Examiner Hadi Shakeri

APPARATUS FOR POLISHING A : MAIL STOP: AF

SUBSTRATE

REQUEST FOR RECONSIDERATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 THE COMMISIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of December 27, 2006, Applicants in the abovereferenced U.S. patent application hereby request reconsideration of the rejections contained therein.

In the Office Action, the Examiner maintained the rejection of claims 44, 49 and 50 along with their respective dependent claims, based upon the combination of Lebel et al., U.S. Patent 6,334,807, in view of Watanabe et al., U.S. Patent 5,951,368. A secondary reference to Osterheld was cited with respect to claims 44-46, as well, it is noted. Watanabe was cited in combination with Shultz, Re. 34,425 to reject claims 50-52. These same claims were also rejected as being unpatentable over Lenkersdorfer in view of Watanabe.

However, it is respectfully submitted that the present invention in fact distinguishes over each combination of references cited by the Examiner. The Examiner relied, in each combination, upon the teachings of Watanabe as controlling the attitude of a top ring with respect to the surface of a turntable.